

















Metrology Advances for Digitized ECS industry 4.0

# **Automotive and Semiconductor Domains** Analogy

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### **MADEin4 Project Essentials**

**Objective and Industry 4.0 boosters** 

**Automotive and Semiconductor domains analogy** 

Data is the new oil: design, modeling, metrology and ML Context creation

**Automotive domain use cases** 

**Summary and Outlook** 



### **MADEin4 Project Essentials**

**Objective and Industry 4.0 boosters** 

# MADEIn4 project essentials

• Number of consortium members: 47

• Countries involved: 10

• Start date: April 1, 2019

• Duration: 36 months

• Total effort: person.months: 10,503 (875 person.years)

• Total H2020 eligible costs: € 126,176,472.50

# MADEIn4 project essentials

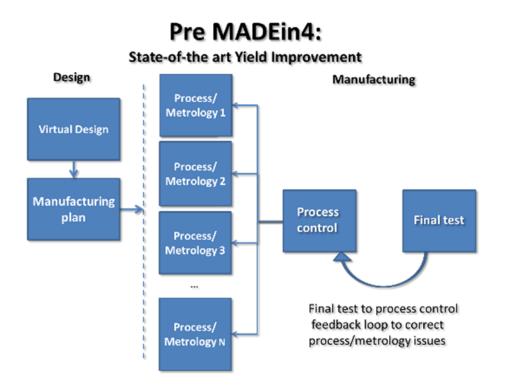


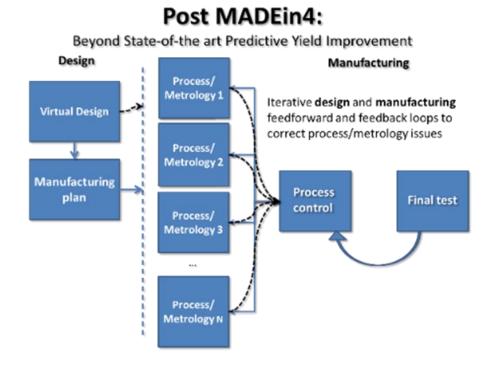
# Objective and Industry 4.0 boosters

Develop and qualify new productivity boosters:

- Booster 1: High-productivity metrology and inspection tools for semiconductor and automotive industry
- Booster 2: Ready for "industry 4.0" Cyber Physical Systems (CPS):
  - Higher data rates and smart acquisition and processing
  - Smart use of data to improve the over-all productivity and predictability







From: reactive manufacturing to predictive manufacturing

Semiconductor

Number of measurements per wafer 10<sup>3</sup>

Wafers per month 10<sup>5</sup>

Number different products  $10^2 < x < 10^3$ 

Highly automated manufacturing

Number of inputs per unit process (features) 10<sup>2</sup>

Manufacturing process longevity much less than 10<sup>1</sup> years

Litho/ SEM

Etch/ **SEM** 

•••

CMP/ Reflectometry **Automotive** 

Number of measurements per car >>10<sup>3</sup>

Doors welding/ Cars per month 10<sup>5</sup> **Optical inspection** 

> Number of different configurations  $10^2 < x < 10^3$

> > Highly automated manufacturing

Number of inputs per unit process (features) 10<sup>2</sup>

Manufacturing process continuously under improvement and changes

Painting/ **Optical inspection** 

**Engines Assembly/ EOL** hot test

11/18/2020

**AEIT 2020** 

#### Post MADEin4 (Semiconductor): Beyond State-of-the art Predictive Yield Improvement Design (EDA) Manufacturing Litho/ SEM Iterative design and manufacturing **Physical Design** feedforward and feedback loops to correct process/metrology issues Etch/ SEM **Mask Synthesis** (Resolution **Electrical** Lot/ enhancement wafer/ test post boosters) CVD/ chip analysis packaging TEM CMP/ OCD

### Post MADEin4 (Automotive):

Beyond State-of-the art Predictive Yield Improvement Virtual Validation Manufacturing **Automotive** manufacturing **Product** Iterative design and manufacturing process 1 Development feedforward and feedback loops to Lifecycle Mgmt correct process/metrology issues Automotive manufacturing **Process** process 2 Simulation and Pass/No **Process Planning** Pass final control **Automotive** Lifecycle Mgmt analysis test manufacturing process 3

**Automotive** 

process N

The Semiconductor and Automotive industries are sharing similar design and manufacturing flows and differ by the content of each of the design and manufacturing modules

This allows to develop innovative shared machine learning based methodologies which will enable the transformation of the manufacturing from reactive to predictive

# AGENDA

Data is the new oil: design, modeling, metrology and ML Context creation

### Data is the new oil

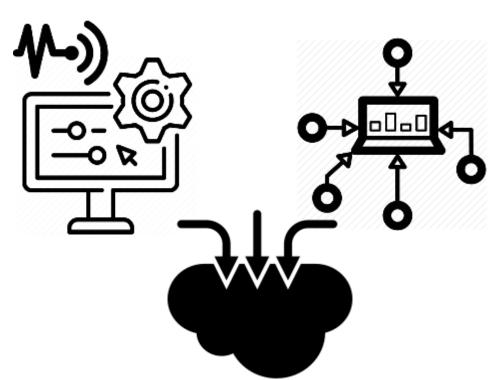
1

Data collected and pushed to the cloud



2

Sensors are added to industrial computers



3

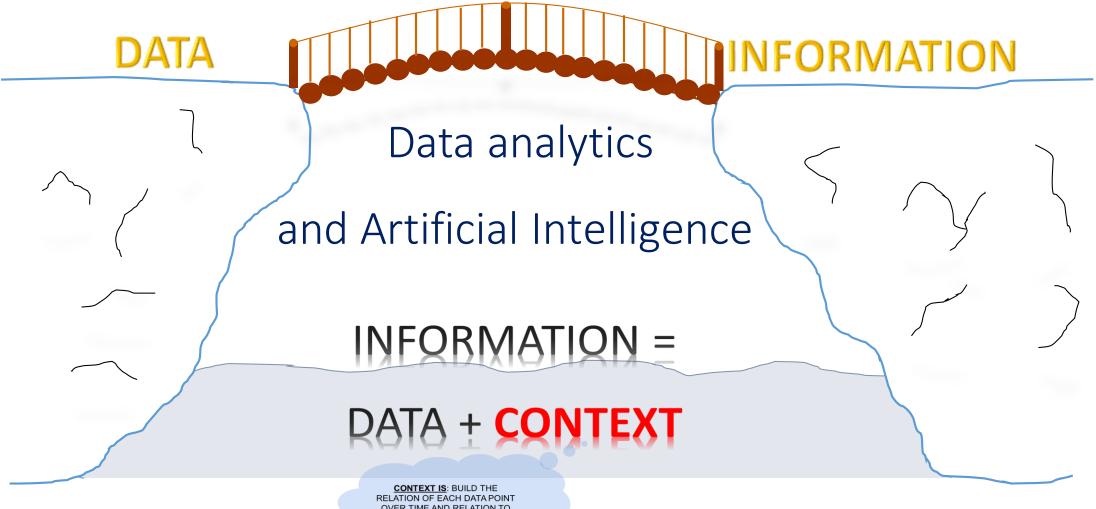
Constant data collection for future possible usage



Data analysis by tailormade algorithms

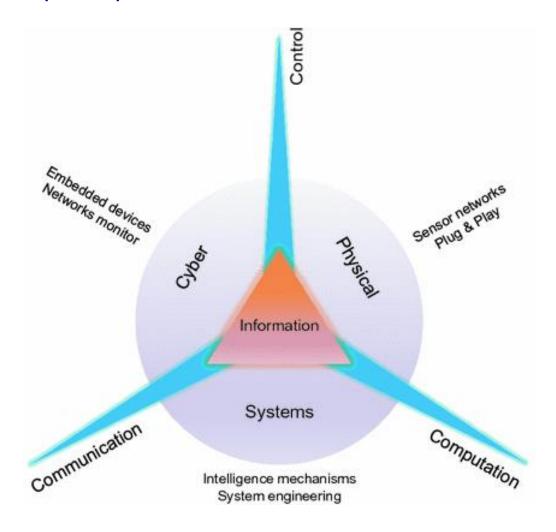


# CONTEXT (crossing) the chasm



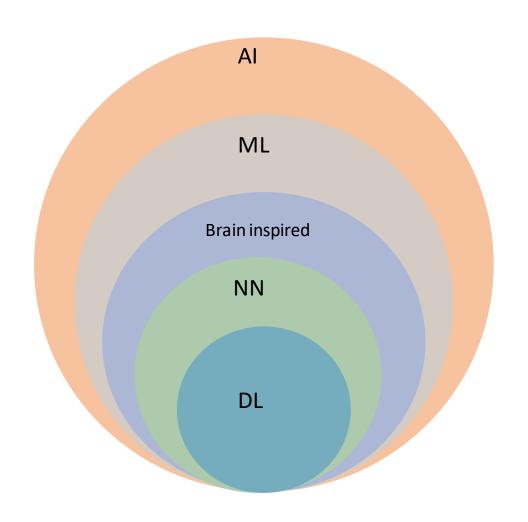
OVER TIME AND RELATION TO **EACHOTHER** 

# Cyber-physical Systems (CPS) for Information Creation



The interaction of physical and computing, including embedded intelligence at all levels

# Artificial Intelligence (AI)



- AI: Artificial intelligence making decisions about a system
- ML: Machine learning modeling the behavior of a system
- NN: Neural networks are one implementation of machine learning
- DL: Deep learning is one implementation of Neural networks

# Digital twinning: Creating a virtual Representation of the Production Process

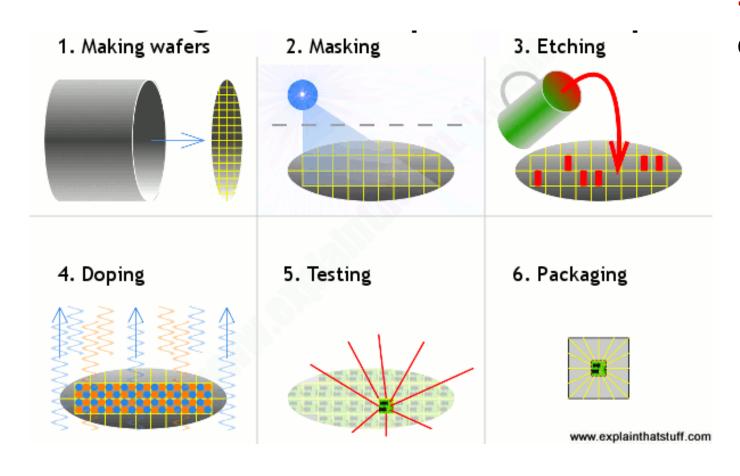
**Traditional modeling**: Physical models requiring little data but deep understanding of the process.

ML-based modeling: "black box" models requiring feature engineering coupled with sensor data.





# CPS SENSORS: From Silicon wafer to IC Processes and Metrology



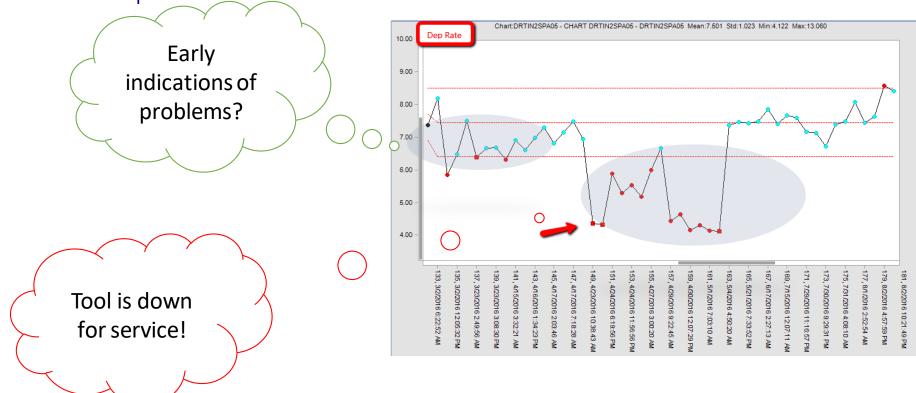
**700 to 1500** operations for an average CMOS process

- 2-3 months manufacturing time
- 22-50 lithography layers
- 20 Diffusion Ops.
- **23-40** implants Ops.
- 13 DRY Etch Ops
- 78 WET Etch Ops
- 21 Thin-Film (metal) Ops.
- 7 CMP (Chemical-Mechanical-Polish)
  Ops.
- 240 Metrology Ops.
- **240 Yield** Ops.

Source: TOWER

### CPS Sensor Pre-Warn

Metrology use case - Metal deposition rate



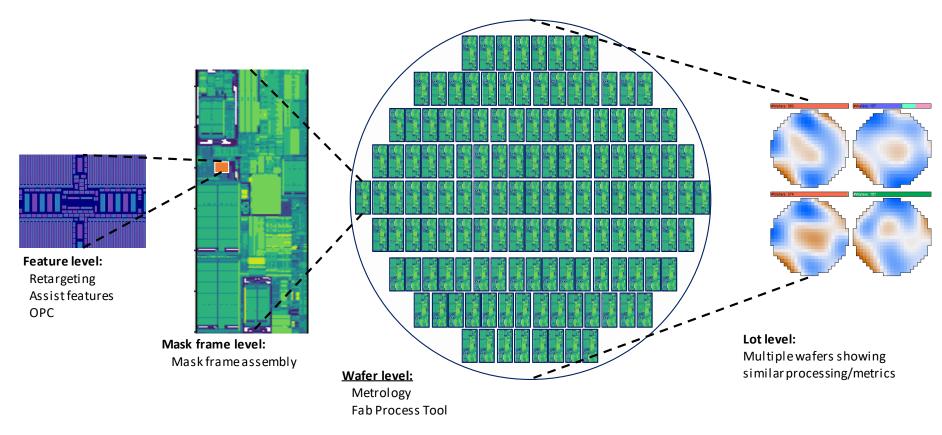
Al to pre-warn about process issues

# Predictive Yield: Feature Engineering

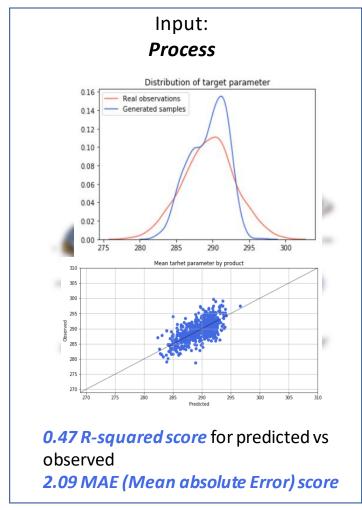
From Feature to Lot level

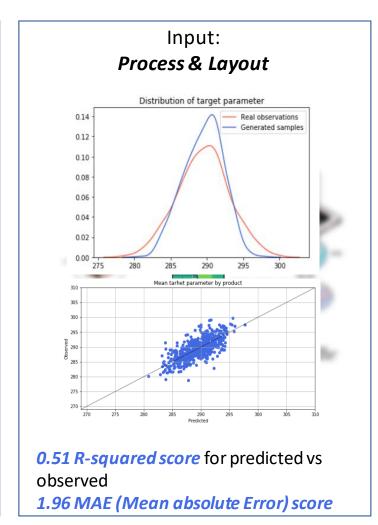
Source: MENTOR

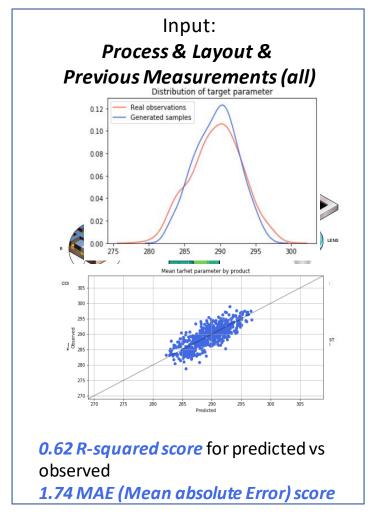
Different processes require their own level of abstraction to capture specific process behavior



### Full process sequence characterization

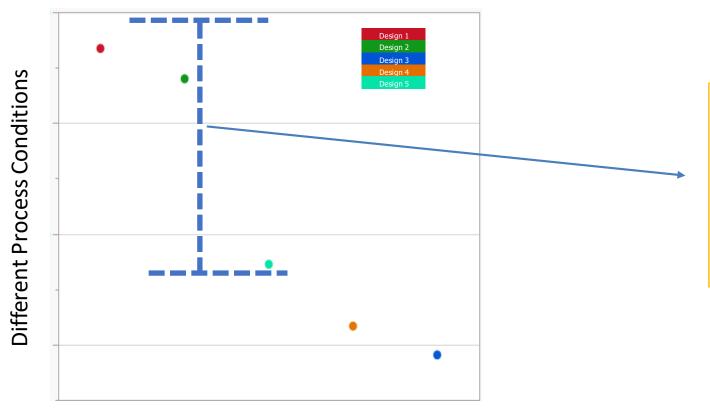






Source: MENTOR

### Digital Twin - Process characterization modeling & optimization



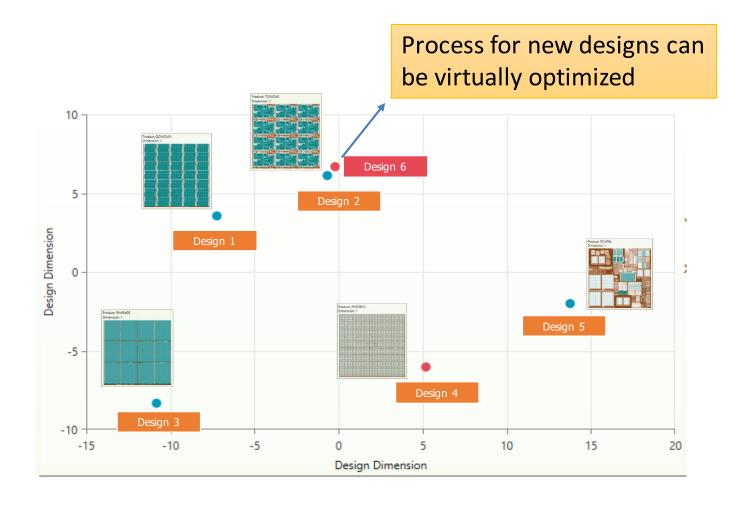
Different designs respond differently to process conditions

They are manually optimized in a time consuming and expensive fashion

**Different Designs** 

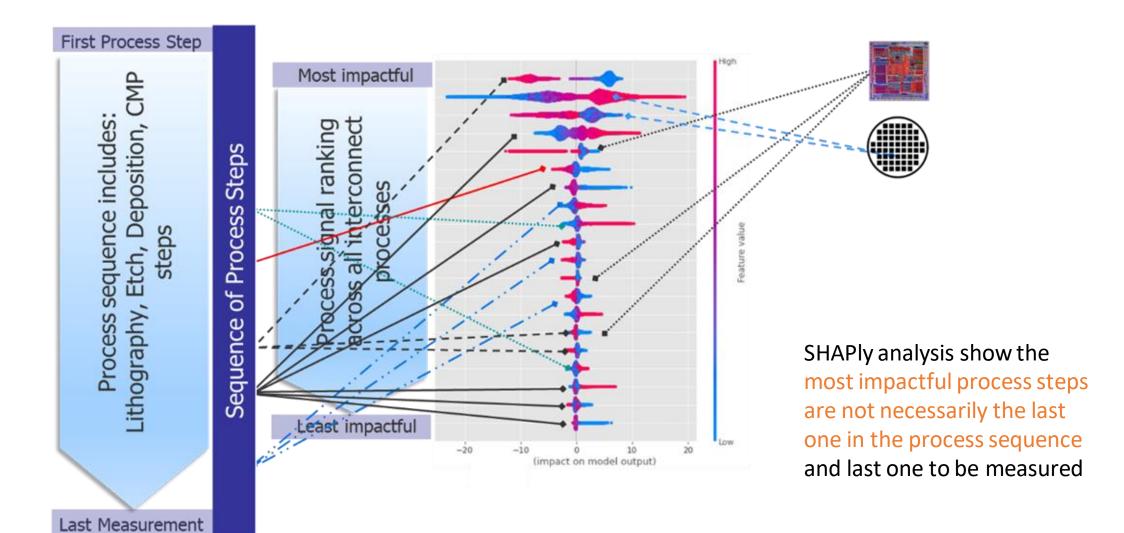
Source: MENTOR

### Digital Twin - Design-aware process optimization



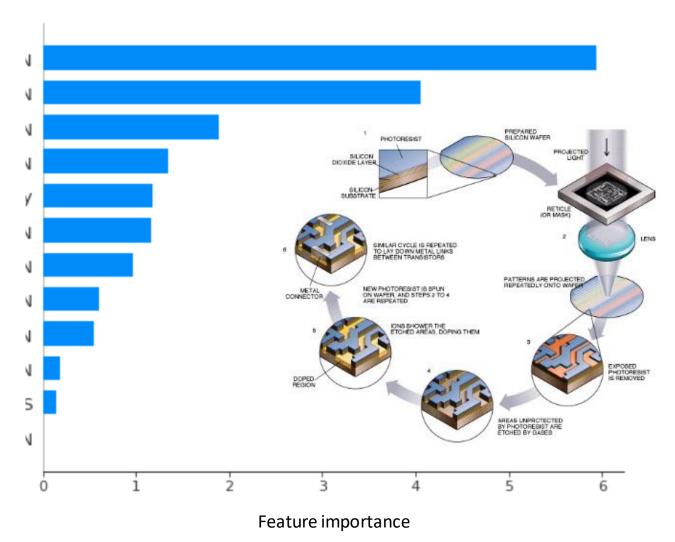
Source: MENTOR

### **Process Impact Analysis**



Source: MENTOR

### Digital Twin Feature Based Yield Prediction



Feature importance assessment to guide correction or define optimal operation

Source: MENTOR

### **Automotive domain use cases**

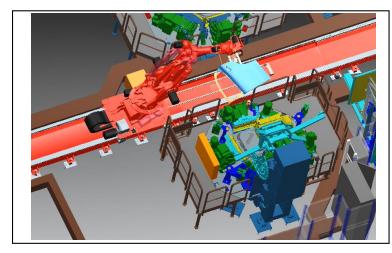
# Use Case 1: Cars body line digitization with Pre-Warn scenarios FCA, NANOMOTION, TOWER, TU DELFT, POLITO

**Problem statement:** door welding defects rarity

**Solution**: development of an inline doors inspection **A**utomated **D**efects **C**lassification (**ADC**)



Weldspots with LED illumination



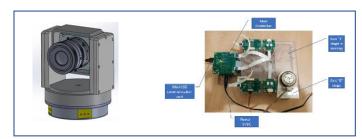
3D Process simulation



Partners test field

Welding doors inspection and ADC flow

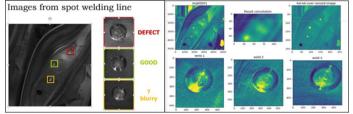
solution and integration Design of innovative



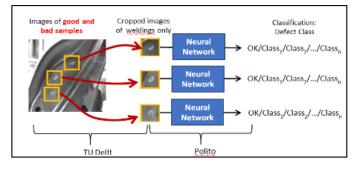
Nanomotion: Camera stabilized gimbal



**TOWER**: sensor and camera



**TUD**: Image conditioning



**POLITO**: Auto Defect classification (**ADC**)

# Use Case 1: Cars body line digitization with Pre-Warn scenarios Automatic Defects Classification in the Semiconductor domain

 ADC is a central server used for Recipe Creation, Runtime Classification & Monitoring in semiconductor manufacturing

- ADC is developed in the Semiconductor domain to:
  - Help semiconductor manufacturers to increase and maintain IC chip yields
  - Monitor whether the process is under control
  - Provide high availability (uptime 99.99%)



Automatic Defects Classification in the Semiconductor domain

 As design rule shrinks, defects hide in inspection noise → the amount of manually classified defects is increasing

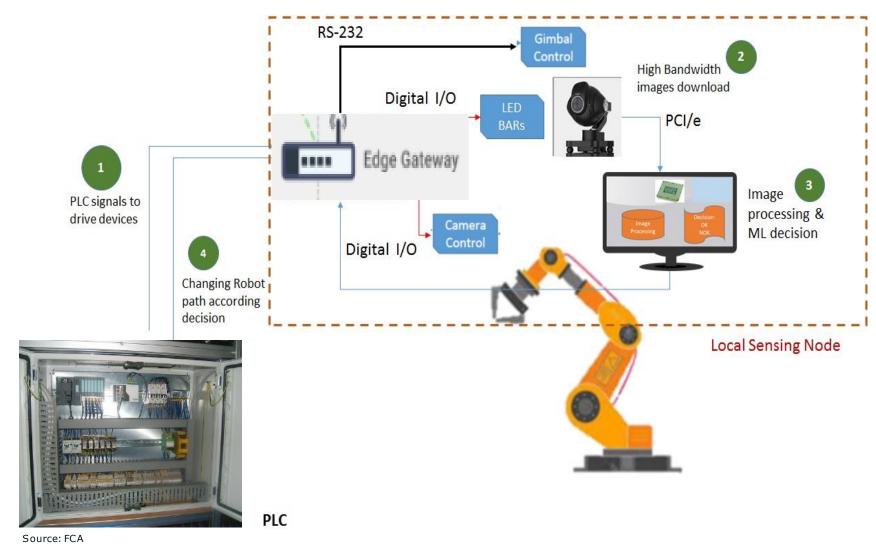


 Classification can be done faster while taking into account much more attributes than human eyes can

High consistency can be reached with an Automatic system

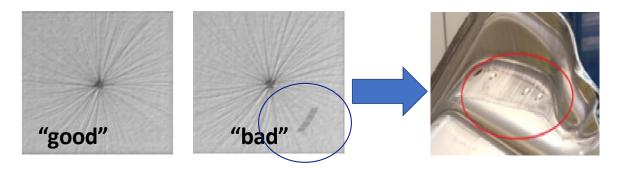


Automotive domain doors inspection and ADC flow overall architecture and processing pipeline



Automatic Defects Classification in the Automotive domain

• Preliminary neural networks (NN) tested both on synthetic and real images

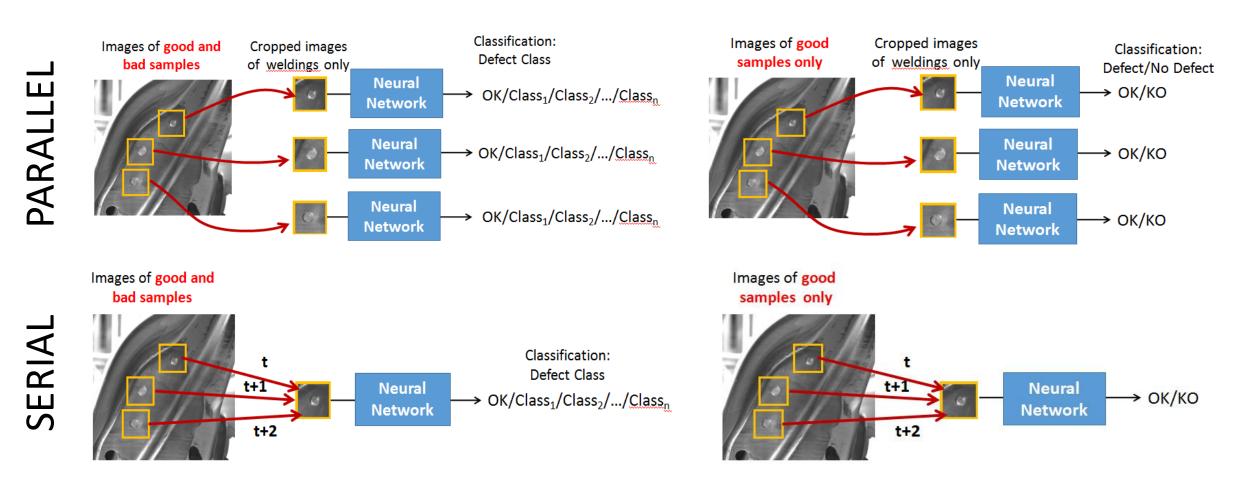


- An independent classification (a distinct network) for each soldering point were used
- Two approaches of NN were compared:
  - One-class classifiers (unsupervised)
    - Uses only ``good'' samples, Classes are OK/KO
  - Traditional multiclass CNN (supervised)
    - Classes can be multiple
- Two different architectures of processing options were tested:
  - Serial
  - Parallel

Choice will depend on the cost (performance) of the overall pipeline of operations (camera, cropping, image processing)

Speed vs. size of the network

Automatic Defects Classification in the Automotive domain



**SUPERVISED** 

**UNSUPERVISED** 

Automatic Defects Classification analogy between Automotive and Semiconductor - Outlook

- Exploring 'SEMI Automotive' ADC potential cross fertilization:
  - Is there potential value in adapting concepts from SEMI to automotive and vice versa?
- Objectives
  - Introduction to SEMI and Automotive ADC concepts, challenges and solutions
  - Potential cross fertilization ideas
- Action:

 Map similarities and differences between SEMI ADC and Automotive ADC: needs, constraints, approaches

# Use case 2: End-of-Line Engines Testbenches AVL, FCA



#### **Problem statement:**

End of Line engines tests efficiency:

- Conducting End Of Line engines hot testbench is expensive (time, effort, ...)
- Hot EoL tests are conducted for 5-10 % of all engines
- Typically engines are selected randomly, this poses the risk that erroneous engines are overlooked

#### **Solution:**

cycle time reduction:

- Reduction of false negatives (healthy engines that are qualified as erroneous) through data-driven selection (correlation of after sale, cold and hot test data)
- Reduction of false positives (erroneous engines that are qualified as healthy) through predictive warning driven from the cold test bench

#### **EoL** cold testbeds



30 secIn-line

#### **EoL** hot testbeds



- ½ h 3 h
- oil, Electronic Control Unit, fire-up, ..

#### **Engine performance testbeds**

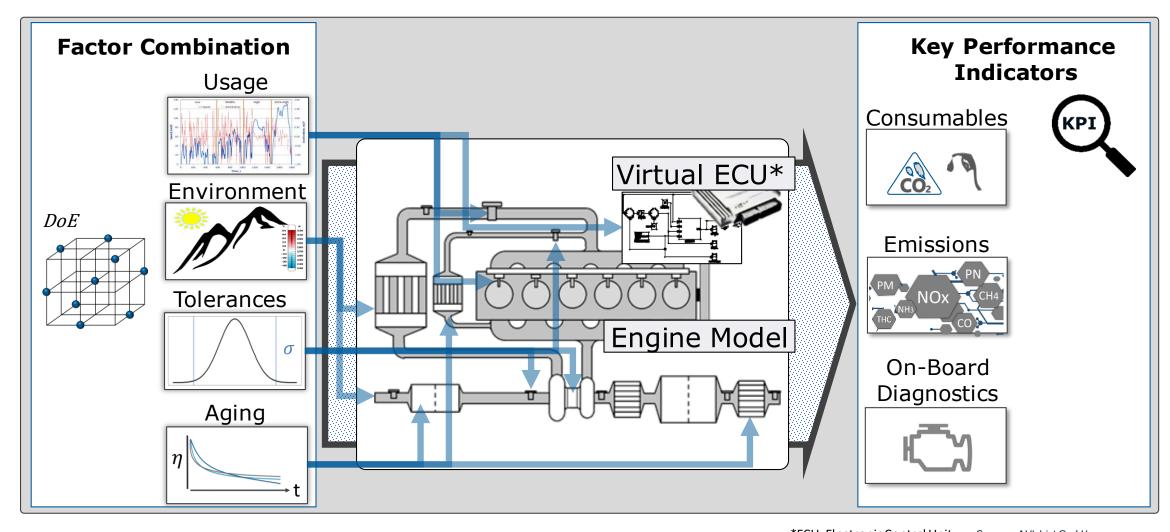




Source: AVL List GmbH

# Use Case 2: EoL Evaluation of the impact on production tolerances on engine KPIs





\*ECU: Electronic Control Unit Source: AVL List GmbH

# Use Case 2: Method EoL Cold/Hot Optimization





(historic data)

#### **EoL cold tests**

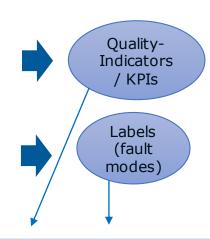




#### **EoL** hot tests



ICE* no.	Ch1 time series	 Ch [30+] time series
E1	1.2, 1.4, 1.7,	1.2, 1.4, 1.7,
E2	0.87, 1.2, 1.7,	0.87, 1.2, 1.7,
E3	0.27, 0.2, 0.7,	0.27, 0.2, 0.7,
En		



ICE no. (subset of EoL cold test)	Label (test oracle)
E1	healthy
E2	erroneous
E3	healthy
Em	erroneous

\*Internal Combustion Engine

Model learning: e.g., classification model  $Y_i = h\left(x_i^{(1)}, x_i^{(2)}, \dots, x_i^{(m)}\right) + E_i$ 

# Use Case 2: Method EoL Cold/Hot Optimization



(live data)



### **EoL** cold tests



ICE no.	Ch1	 Ch [30+]
E1	1.2, 1.4, 1.7,	1.2, 1.4, 1.7,
E2	0.87, 1.2, 1.7,	0.87, 1.2, 1.7,
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En		



### **EoL** hot tests

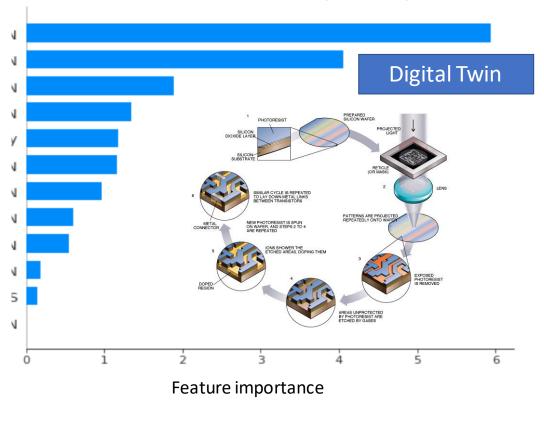


ICE no.	False positive/ False negative
E1	healthy
E2	erroneous engines qualified as healthy
E18	healthy
Em	Healthy engine qualified as erroneous

$$Y_i = h\left(x_i^{(1)}, x_i^{(2)}, \dots, x_i^{(m)}\right) + E_i \rightarrow \text{prediction}$$

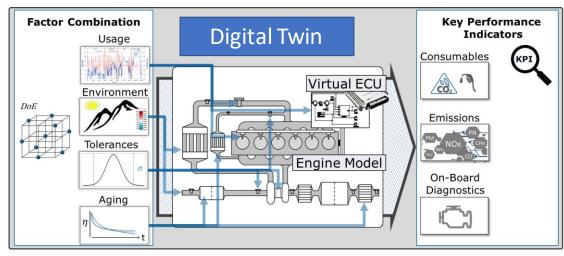
# Use Case 2: Automotive / Semiconductor Predictive Analysis Analogy

### Semiconductors wafers features process prediction



Source: MENTOR

### Automotive engines features process prediction



ICE no.	False positive/ False negative
E1	healthy
E2	erroneous engines qualified as healthy
E18	healthy
Em	Healthy engine qualified as erroneous

Source: AVL List GmbH

# Summary and Outlook

- Data is the new oil and data analytics with artificial intelligence uses context to produce information
- Analogies between the Semiconductors and Automotive domains could enable cross fertilization between the two
- MADEin4 is expected to make a breakthrough for yield prediction and pre-warn scenarios accuracy and cycle time in both the Semiconductors and Automotive domains by:
  - Enhanced methodologies, algorithms and hardware such the case of automatic defects classification (ADC) in the production line
  - Improved digital twin modeling accuracy with design, process and metrology data from various sources

















# ADEin4

# Thank You For Your Attention

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